

RESPONSE UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2624

PATENT APPLICATION
Docket No.: 2522-047
Client Ref. No. AW8085US/EK

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Deok-Yong KIM

Serial No.: 10/749,670 Examiner: Dennis ROSARIO

Filed: December 30, 2003 Art Unit: 2624

Confirmation No.: 9761

For: METHOD AND APPARATUS FOR DETECTING DEFECTS ON A
WAFER

Date: November 27, 2007

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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR 1.116

Responsive to the Final Office Action, Paper No. 20071004, dated October 15, 2007,
please amend the application as follows.

- **Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.
- **Remarks/Arguments** begin on page 6 of this paper.